



Docket No. 51380

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Takashi et al.

SERIAL NO. 10/078,766

GROUP: 1742

FILED: February 19, 2002

EXAMINER: W. Leader

FOR: PROCESS FOR ELECTROPLATING SILICON WAFERS

Mail Stop: RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Applicants file herewith a Request for Continued Examination (RCE). Please amend the application as follows.

A listing of pending claims begins on page 2 of this paper.

Remarks begin on page 4 of this paper.